

Fabrication of CIGS films by using MBE for tandem solar cells

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Experimental

Growth method: conventional Molecular beam epitaxy Sources: Cu(7N), In (7N), Se(6N) Substrate: Ge (001) Growth temperature: 450°C Cu/In ratios: γ =0.4-2.2(changing the In beam flux) Substrate etching solution: 1HF:1H₂O₂:30H₂O Thermal cleaning process : 640°C Characterization: XRD, RHEED, SEM,EPMA

<RHEED patterns from thermal clean Ge(001) surface>











Near stoichiometric CIS film was not observed second phase

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CuInSe₂ (CIS) films with Cu/In ratios of γ =0.4-2.2 have been grown on (001)-oriented Ge substrates by molecular beam epitaxy at substrate temperature of T_s=450 °C.

In situ RHEED analysis indicated the epitaxial growth as well as the chalcopyrite structure.

RHEED patterns along the [-100] direction showed the spots characteristic of the chalcopyrite structures, also indicating the c-axis normal to the substrate.

No secondary phase detected in XRD at Cu-rich and near stoichiometric but In-rich CIS films were observed.